

# Seokhwan Bang

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/7770715/publications.pdf>

Version: 2024-02-01

10  
papers

324  
citations

1163117

8  
h-index

1372567

10  
g-index

10  
all docs

10  
docs citations

10  
times ranked

683  
citing authors

#	ARTICLE	IF	CITATIONS
1	A study on H <sub>2</sub> plasma treatment effect on a-IGZO thin film transistor. Journal of Materials Research, 2012, 27, 2318-2325.	2.6	83
2	Photocurrent detection of chemically tuned hierarchical ZnO nanostructures grown on seed layers formed by atomic layer deposition. Nanoscale Research Letters, 2012, 7, 290.	5.7	76
3	The effect of oxygen remote plasma treatment on ZnO TFTs fabricated by atomic layer deposition. Physica Status Solidi (A) Applications and Materials Science, 2010, 207, 1845-1849.	1.8	60
4	AZO/Au/AZO multilayer as a transparent conductive electrode. Physica Status Solidi (A) Applications and Materials Science, 2012, 209, 698-701.	1.8	35
5	Dual optical functionality of local surface plasmon resonance for RuO <sub>2</sub> nanoparticle@ZnO nanorod hybrids grown by atomic layer deposition. Journal of Materials Chemistry, 2012, 22, 14141.	6.7	21
6	The effects of a HfO <sub>2</sub> buffer layer on Al <sub>2</sub> O <sub>3</sub> -passivated indium-gallium-zinc-oxide thin film transistors. Physica Status Solidi - Rapid Research Letters, 2011, 5, 403-405.	2.4	14
7	Drain-Induced Barrier Lowering in Oxide Semiconductor Thin-Film Transistors With Asymmetrical Local Density of States. IEEE Journal of the Electron Devices Society, 2018, 6, 830-834.	2.1	10
8	Role of postannealing temperature on the microstructure of Al <sub>2</sub> O <sub>3</sub> /ZnO thin films grown by atomic layer deposition for TFT applications. Physica Status Solidi (A) Applications and Materials Science, 2010, 207, 2185-2189.	1.8	9
9	Effects of atomic layer deposition temperatures on structural and electrical properties of ZnO films and its thin film transistors. Metals and Materials International, 2010, 16, 953-958.	3.4	8
10	Microstructural characterization at the interface of Al <sub>2</sub> O <sub>3</sub> /ZnO/Al <sub>2</sub> O <sub>3</sub> thin films grown by atomic layer deposition. Physica Status Solidi (B): Basic Research, 2011, 248, 1634-1638.	1.5	8